

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT (USE SEVERAL SHEETS IF NECESSARY)	ATTY. DOCKET NO. MICRON.009DV1	APPLICATION NO. 08/932,228
	APPLICANT Schuegraf, et al.	
	FILING DATE September 17, 1997	GROUP Unknown

U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
<u>Vh</u>		4502914	03/05/85	Trumpp et al.	438	424	—
<u>Vh</u>		5087586	02/11/92	Chan et al.	438	429	—
<u>Vh</u>		5169491	12/08/92	Doan	438	693	—
<u>Vh</u>		5191509	03/02/93	Wen	257	304	—
<u>Vh</u>		5302233	04/12/94	Kim et al.	438	692	—
<u>Vh</u>		5366590	11/22/94	Kadomura	438	723	—
<u>Vh</u>		5470783	11/28/95	Chiu et al.	438	446	—
<u>Vh</u>		5530293	06/25/96	Cohen et al.	257	752	—

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)	
<u>Vh</u>	1.	Kirk-Othmer, Encyclopedia of Chemical Technology, Second Completely Revised Edition, Vol. II, 1966, pp. 791-792.
	2.	Silicon Processing for the VLSI ERA, Isolation Technologies for Integrated Circuits, Vol. II, Ch. 2, pp. 12-83

EXAMINER HUNG K. VO	DATE CONSIDERED 08/02/98
*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED. INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.	